**Supplementary Materials**

**Fabrication of Polymer Microstructures of Various Angles via Synchrotron X-Ray Lithography Using Simple Dimensional Transformation**

![Experimental chamber](image1)

**Figure S1.** Experimental chamber. (a) Schematics of the experimental chamber, (b) Picture of the experimental chamber.

![Microstructure](image2)

**Figure S2.** Photograph of the microstructure. (a) View from 45°, (b) View from almost 90°.

![Attachment of PI film](image3)

**Figure S3.** Schematics of attachment of PI film on the Al support.

![Fabrication process](image4)

**Figure S4.** Fabrication process of the electroplated mold. (a) Schematic of the tilted microstructure on the PI film, (b) Schematic of the Au electroplating on the PI film, (c) Picture of the electroplated mold with tilted microstructures.
Table S1. Sampled measured angle, measured position of the microstructures, and the calculated position.

<table>
<thead>
<tr>
<th>Measured Angle (°)</th>
<th>43.9</th>
<th>26.0</th>
<th>5.6</th>
<th>−13.6</th>
<th>−32.1</th>
<th>−45.6</th>
</tr>
</thead>
<tbody>
<tr>
<td>Measured position (mm)</td>
<td>14.4</td>
<td>8.0</td>
<td>1.6</td>
<td>−4.8</td>
<td>−11.2</td>
<td>−16.0</td>
</tr>
<tr>
<td>Calculated position (mm)</td>
<td>19.2</td>
<td>11.3</td>
<td>2.5</td>
<td>−5.9</td>
<td>−14.0</td>
<td>−19.9</td>
</tr>
</tbody>
</table>

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